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# OFETs as physical sensors

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Ph.D. Course – Bioengineering and robotics (XXX cycle)

# Outline

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What is a physical sensor?

Organic technology VS Inorganic technology

Temperature and force sensor

OFETs as physical sensors

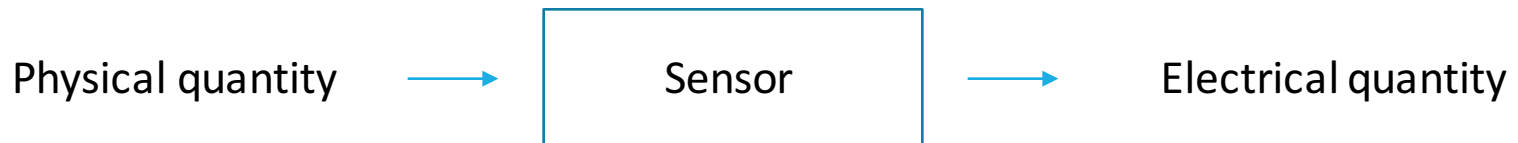
Organic Charge Modulated FET (OCMFET)

OCMFETs as physical sensors

# What is a physical sensor?

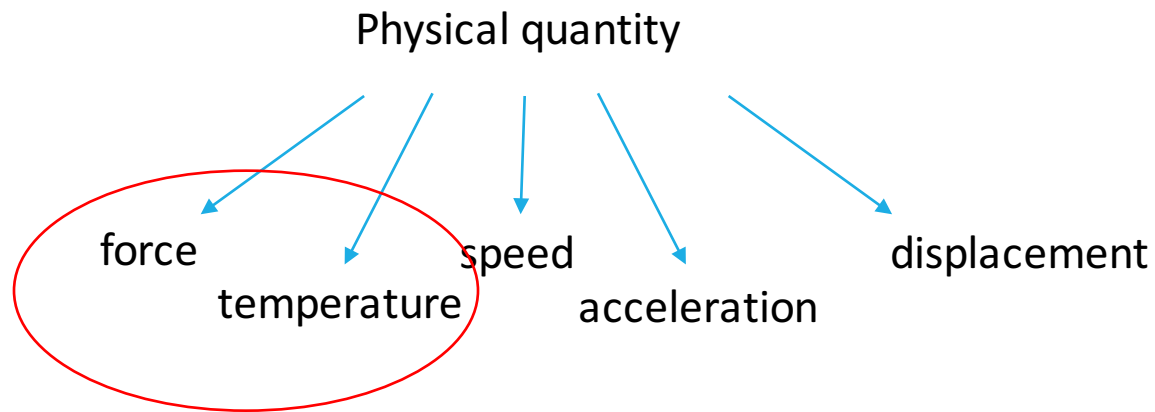
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- A sensor is a part of a Measurement System whose purpose is to detect events and convert them into signals which can be read by an observer or an instrument

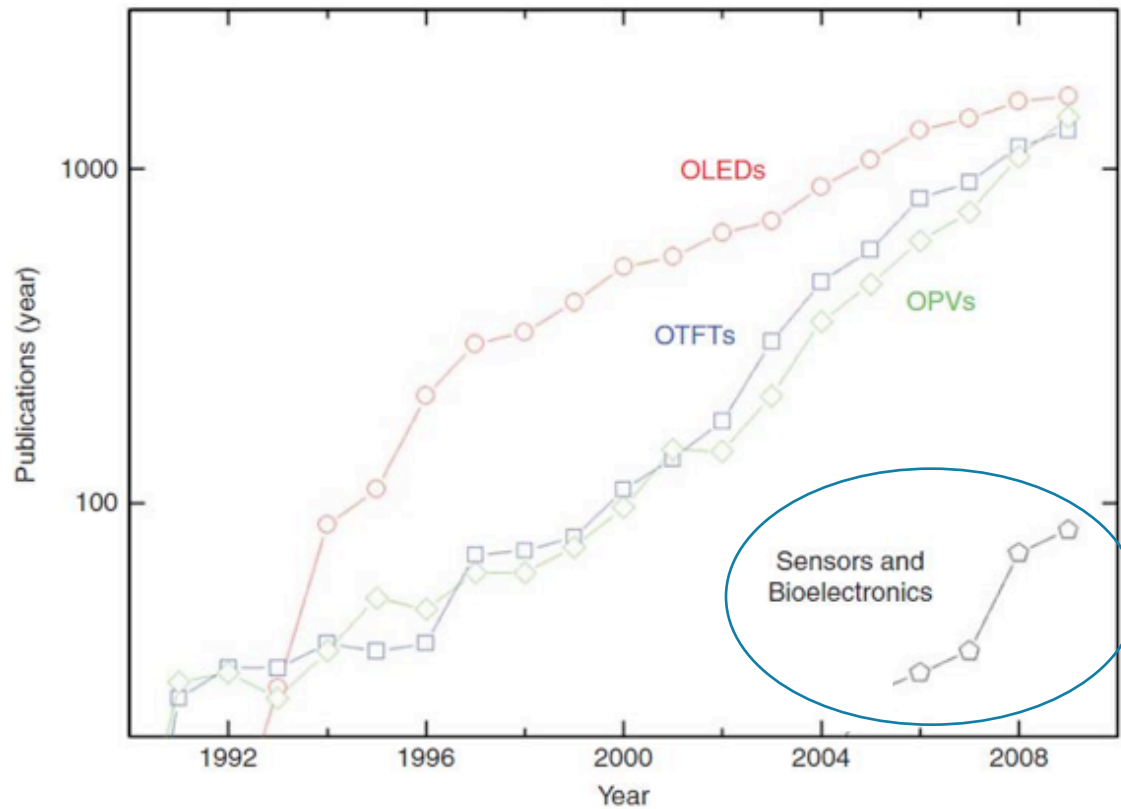


# What is a physical sensor?

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# Temperature and force sensors



# Organic technology VS Inorganic technology

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## ORGANIC:

- Fabrication process @ low temperature
- Low cost
- Thin and flexible films
- Tunable electrical properties

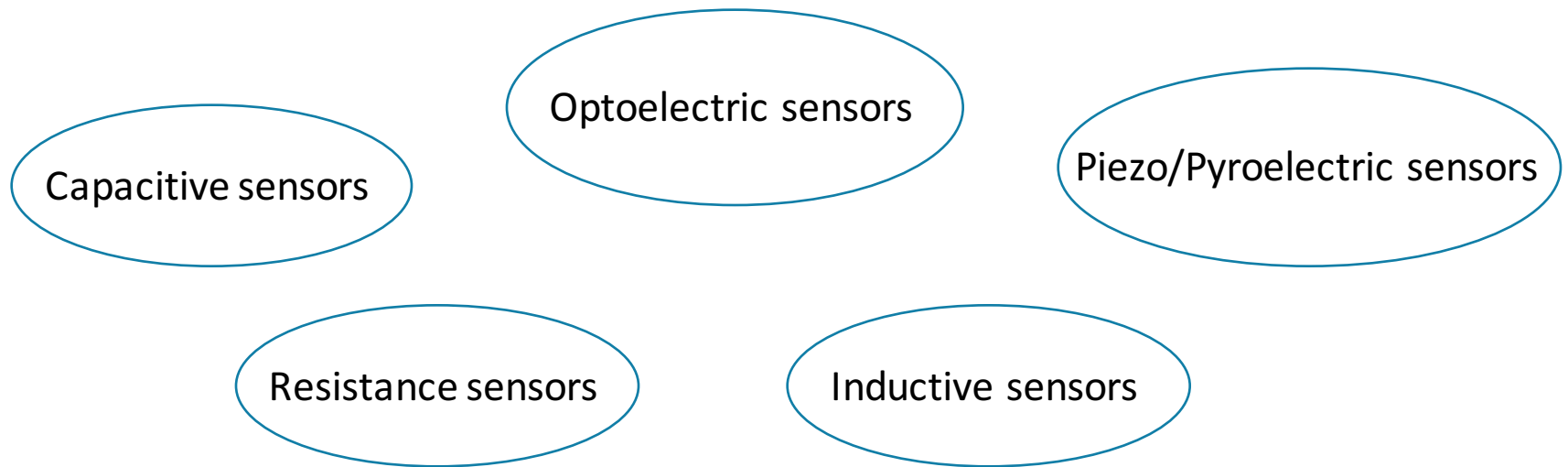
## INORGANIC:

- High performances
- High reproducibility
- Stability in ambient condition
- High integration

# Temperature and force sensors

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- Depending on the transduction mechanism we can divide Physical Sensor into different categories:



# Temperature and force sensor

Transduction technique	Modulated parameter	Advantages	Disadvantages
Capacitive	Change in capacitance	Excellent sensitivity Good spatial resolution Large dynamic range	Stray capacitance Noise susceptible Complexity of measurement electronics
Piezoresistive	Changed in resistance	High spatial resolution High scanning rate in mesh Structured sensors	Lower repeatability Hysteresis Higher power consumption
Piezoelectric	Strain (stress) polarization	High frequency response High sensitivity High dynamic range	Poor spatial resolution Dynamic sensing only
Inductive LVDT	Change in magnetic coupling	Linear output Uni-directional measurement High dynamic range	Moving parts Low spatial resolution Bulky Poor reliability More suitable for force/torque measurement applications
Optoelectric	Light intensity/spectrum change	Good sensing range Good reliability High repeatability High spatial resolution Immunity from EMI	Bulky in size Non-conformable

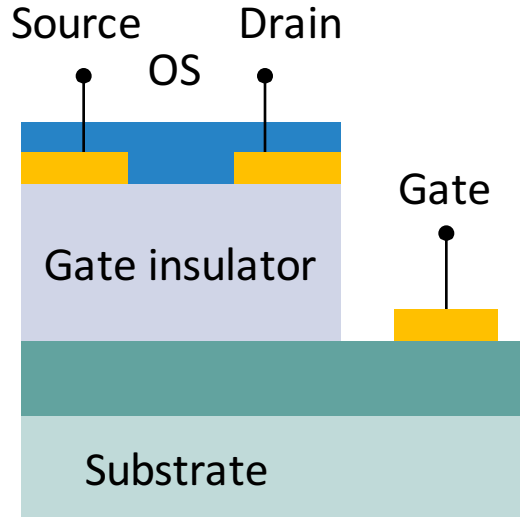
[1] Tiwana et al. *Sensors and Actuators A* 179, (2012) 17-31



# OFET as physical sensor

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It's a three terminal structure, in which a voltage applied to the gate can affect the current flowing between source and drain electrodes (when a  $V_{DS}$  is applied)



$$I_{DS} = f(\mu, C_{ins}, W, L, V_{GS}, V_{DS}, V_{th}, R_C)$$

## Advantages

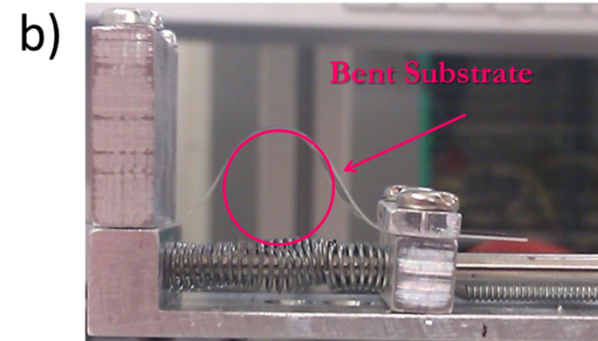
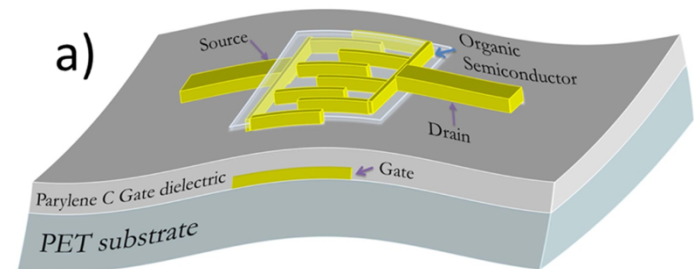
- Low power dissipation
- Local amplification
- Multiparameter device

# OFET as physical sensor

$$\text{Strain} = \left( \frac{d_l + d_s}{2 * R} \right) \frac{(1 + 2\eta + \chi\eta^2)}{(1 + \eta)(1 + \chi\eta)}$$

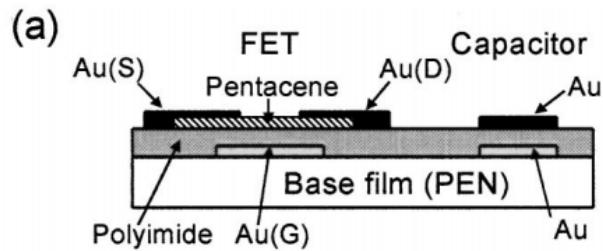


$$\text{Strain} \sim \left( \frac{d_s}{2 * R} \right)$$

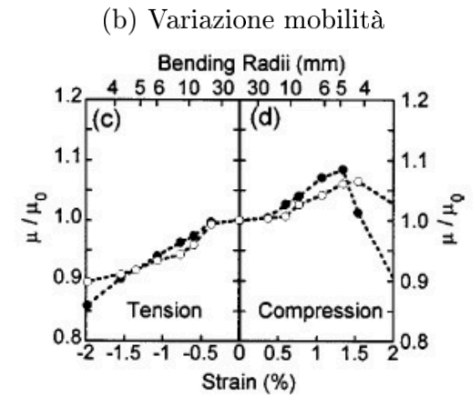
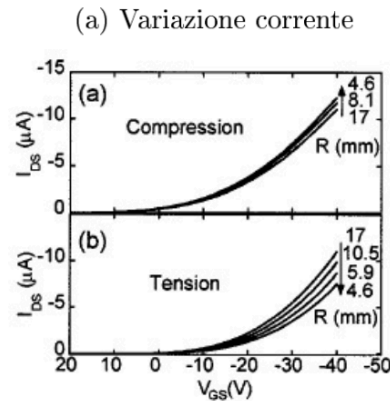


In which  $d_l$  and  $d_s$  are the thicknesses of the layer and of the substrate respectively,  $\eta$  is  $d_l/d_s$ ,  $\chi$  is the ratio between the Young moduli of the layer and of substrate ( $\chi = Y_l/Y_s$ ) and  $R$  is the bending radius

# OFET as physical sensor



Applying a tensile (compressive) stress a decrease (increase) in  $I_{DS}$  was observed

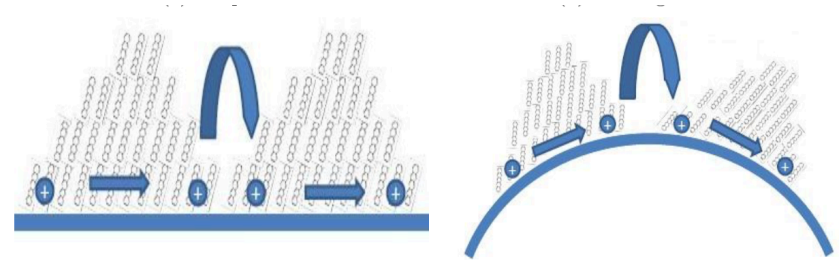
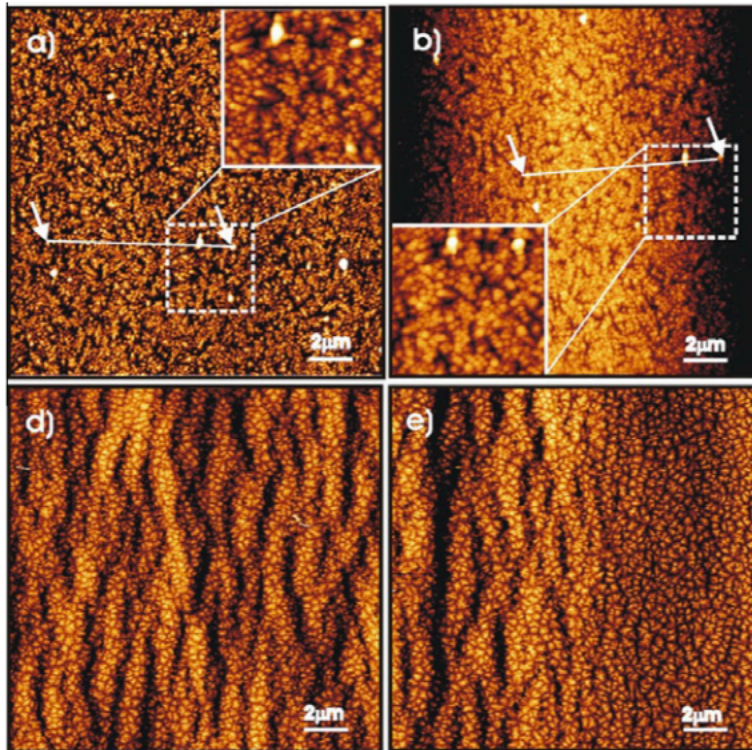


This phenomenon can be attributed to a **variation of the active layer morphological and/or structural properties of the semiconductor film**

$$\mu \sim \mu_0 \exp\left(\frac{-\Delta E}{k_B T}\right)$$

$$\Delta E \propto -k_B T \ln(1 + 0.05\epsilon)$$

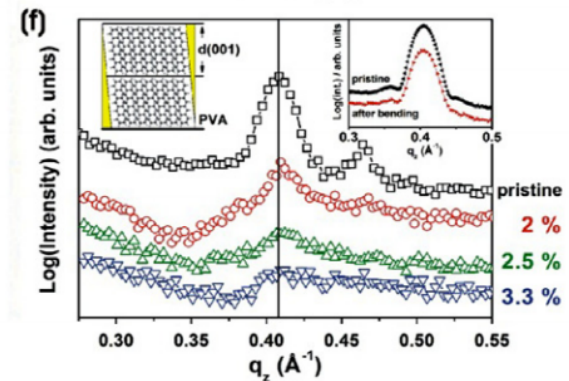
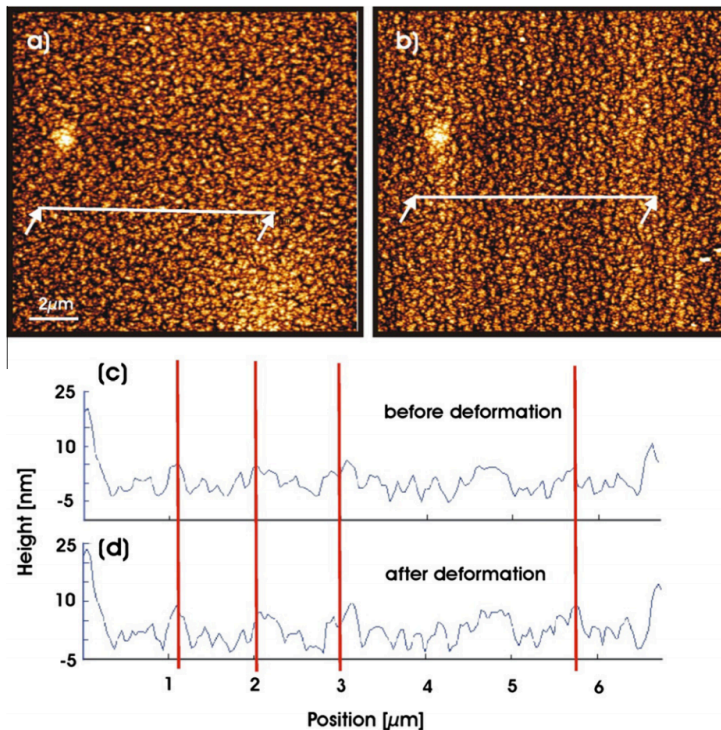
# OFET as physical sensor



Response is more related to  
MORPHOLOGICAL CHANGES

Strains larger than 2% cause the  
formation of cracks within the gold  
electrodes on top of Pentacene film

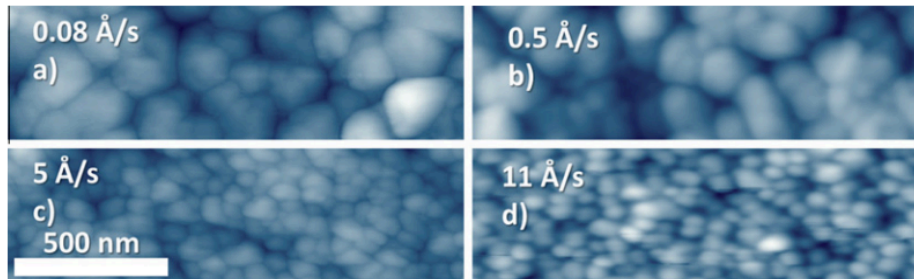
# OFET as physical sensor



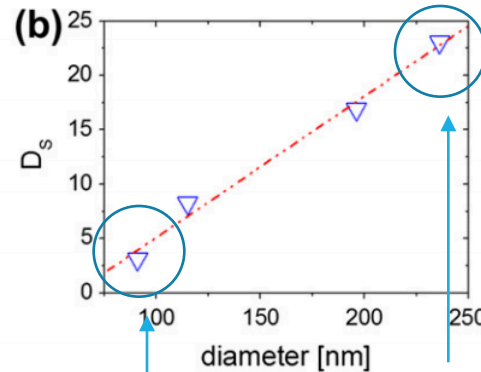
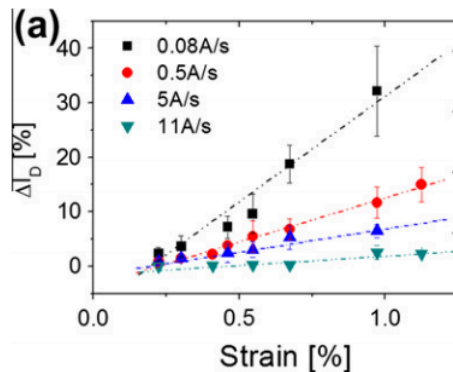
Reversible deformation up to 10% occurs for Pentacene on PVA substrates

Tensile stress leaves the crystal structure unaffected: no phase transitions were observed

# OFET as physical sensor



Can morphological properties cause changes in sensitivity of organic semiconductors to mechanical deformations?



Low sensitivity:  
Flexible electronics

High sensitivity:  
Sensor applications

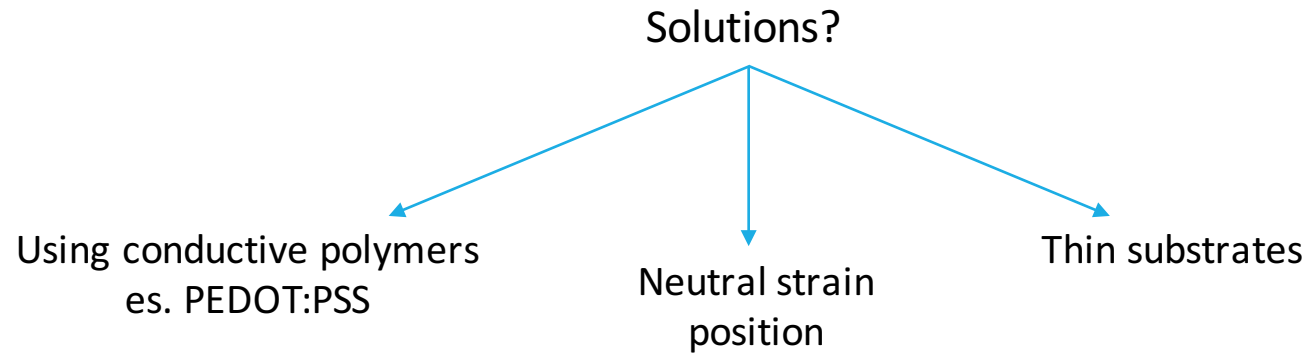
The influence of mechanical deformation on the electrical behavior of OTFTs based on Pentacene is strongly related to the morphological properties

Modulating the Pentacene morphology, it is possible to tune the sensitivity to surface strain in a predictable way

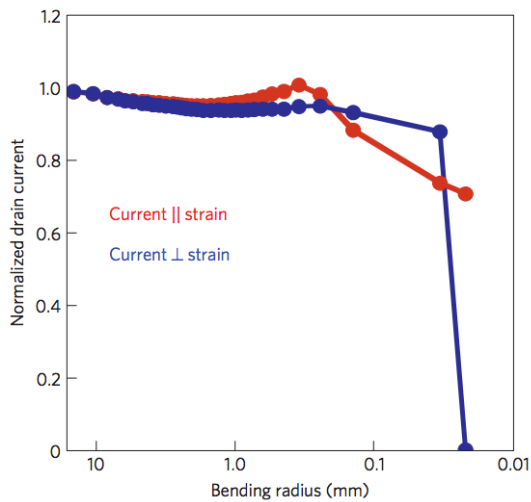
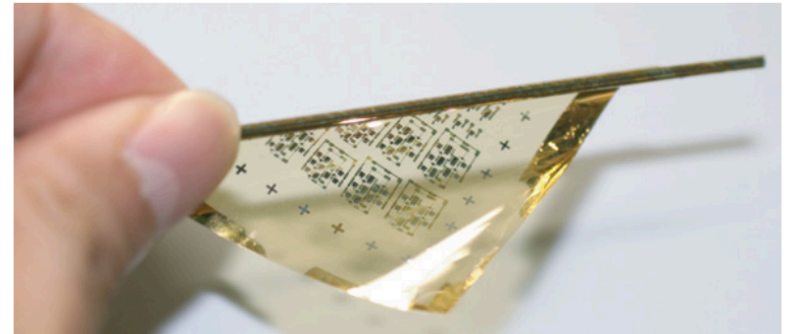
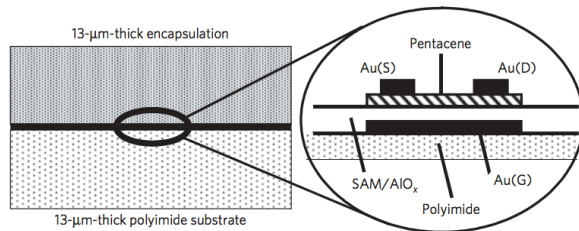
# OFET as physical sensor

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Strains larger than 2% cause the formation of cracks within the gold electrodes on top of Pentacene film



# OFET as physical sensor




TFTs and circuits are located in the neutral strain position (where bending induced compressive and tensile strain cancel each other)

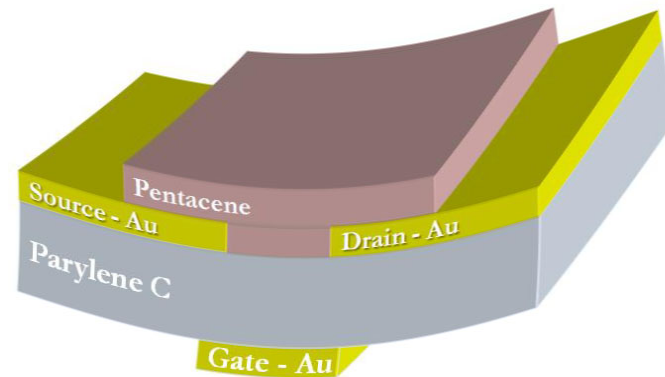
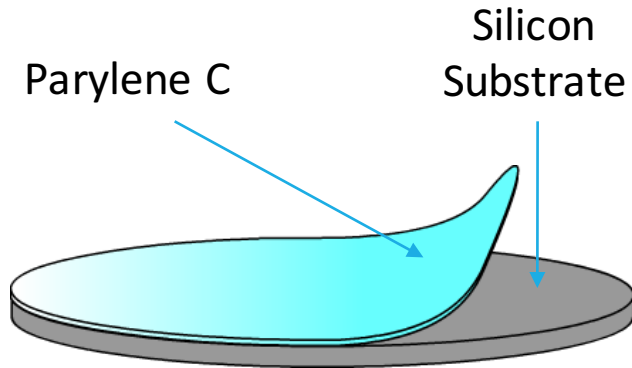
The devices into the neutral strain position operate reliably and with excellent performance characteristics while being folded into a bending radius as small as 100  $\mu\text{m}$



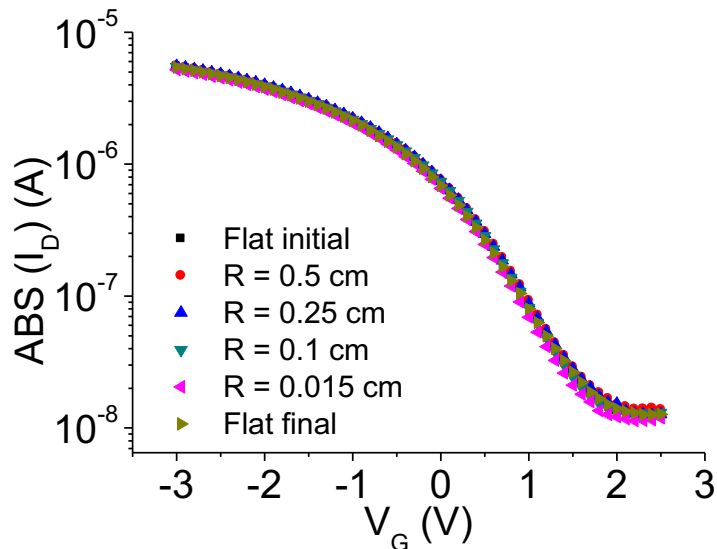
# OFET as physical sensor

$$\text{Strain} \sim \left( \frac{d_s}{2 * R} \right)$$


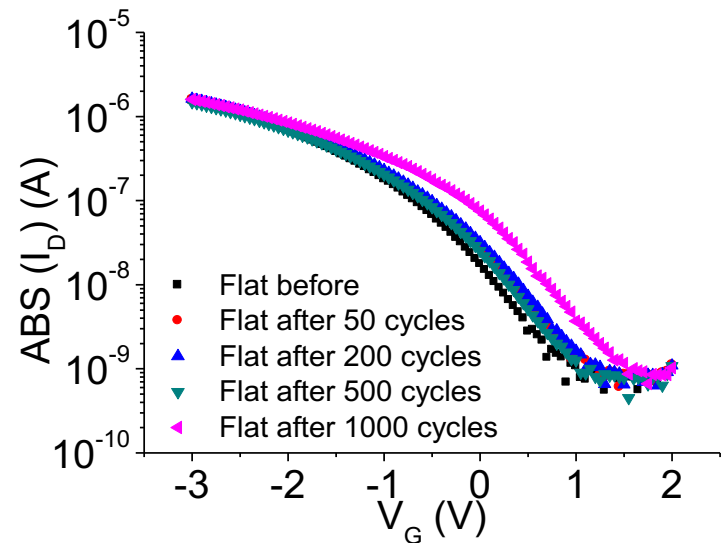
Surface strain depends on the bending radius, but also on the substrate thickness!!!



# OFET as physical sensor

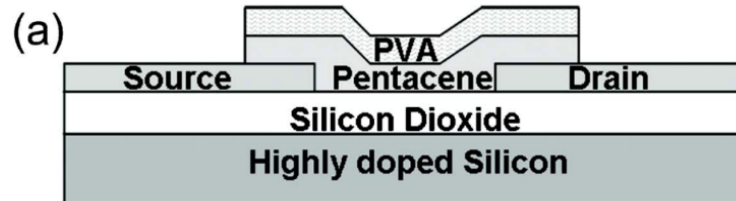


Substrate thickness: 400nm vs 175 $\mu$ m much lower surface strain for the same applied bending radius

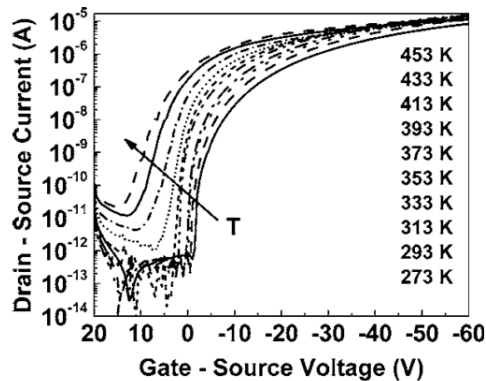


Electrical performances are not affected by mechanical deformation

# OFET as physical sensor



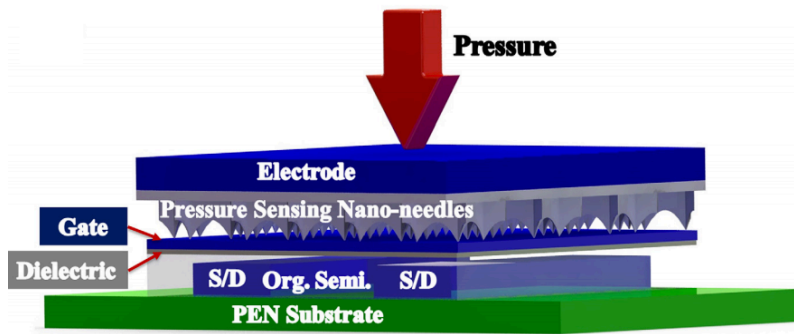
$$\mu \sim \mu_0 \exp\left(\frac{-\Delta E}{k_B T}\right)$$



The variation in the subthreshold drain current can be employed as a temperature sensing operation mode

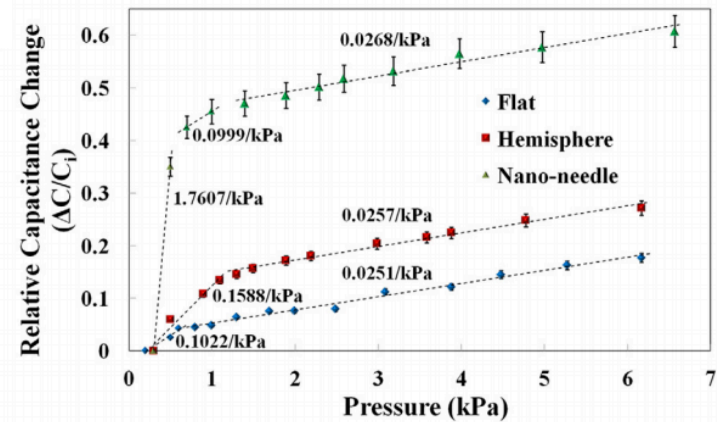
The saturation current shows very little change compared to the subthreshold current

# OFET as physical sensor



The capacitive pressure sensor was integrated with printed organic thin film transistors to enable flexible, large-area tactile sensing applications

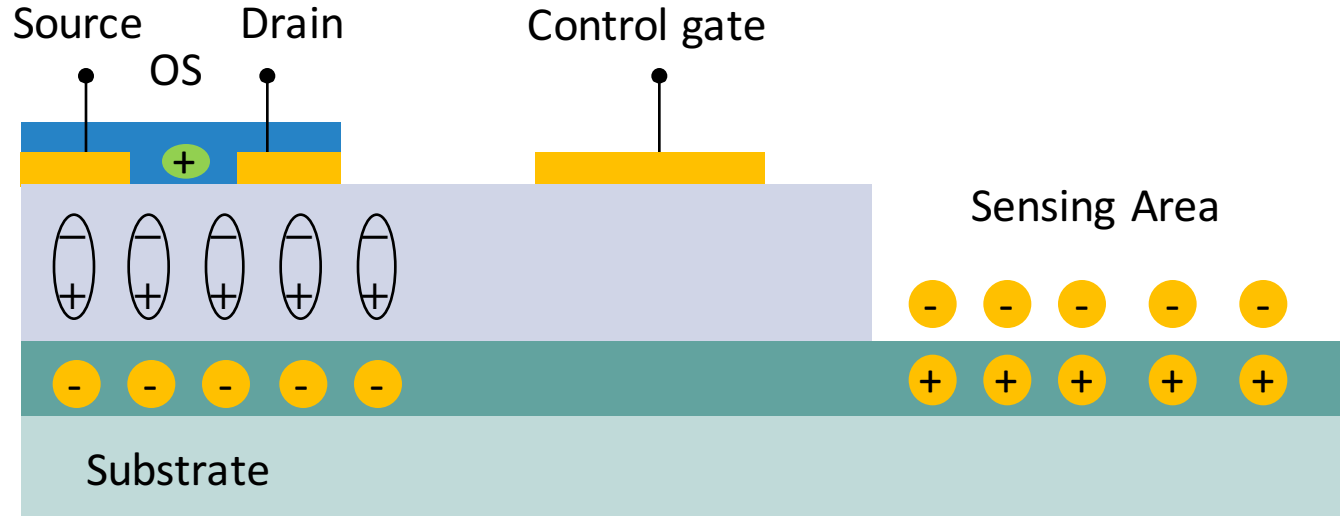
The pressure sensitivity of the sensor, in the low pressure range (<1kPa), is comparable to the sensitivity of human skin



Depending on the type of dielectric it's possible to change the sensitivity

# From OFET to OCMFET

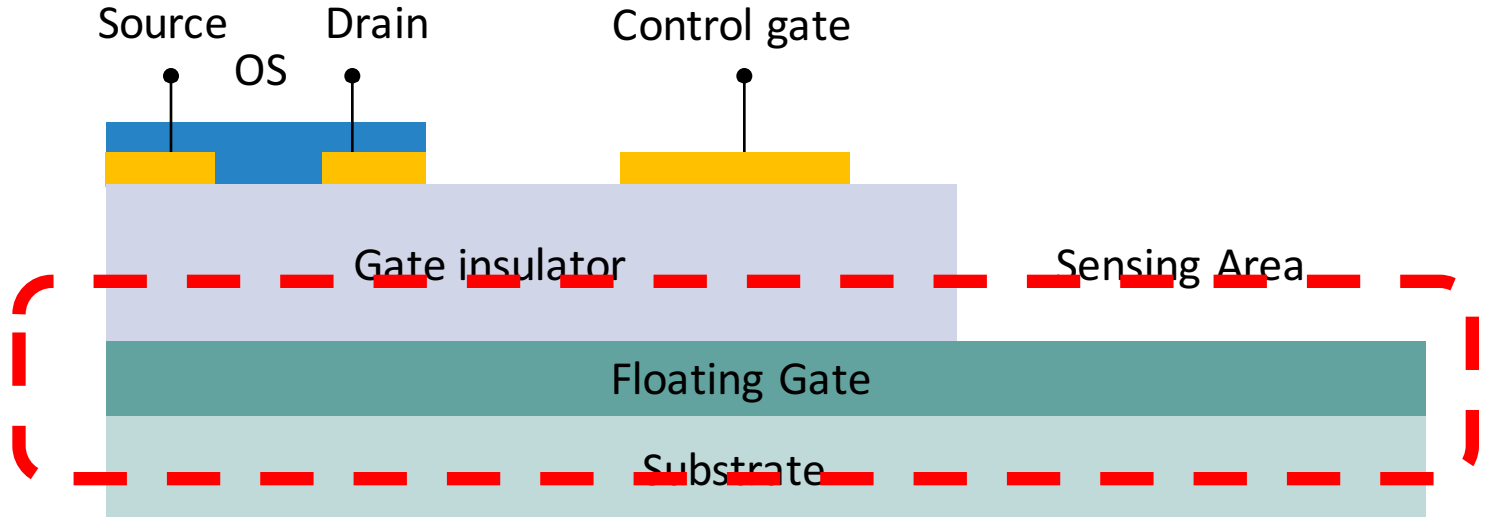
Is a floating-gate transistor, biased through a control capacitor, that is used as a charge sensor



# Organic Charge Modulated FET (OCMFET) – Working principle

$$Q_F = C_{CF}(V_F - V_C) + C_{SF}V_F + C_{DF}(V_F - V_D) + Q_I$$

$$V_F(C_{CF} + C_{SF} + C_{DF}) = (Q_F - Q_I) + C_{CF}V_C + C_{DF}V_D$$



# Organic Charge Modulated FET (OCMFET) – Working principle

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$$Q_F = C_{CF}(V_F - V_C) + C_{SF}V_F + C_{DF}(V_F - V_D) + Q_I$$

$$V_F(C_{CF} + C_{SF} + C_{DF}) = (Q_F - Q_I) + C_{CF}V_C + C_{DF}V_D$$

$$V_F = + \frac{C_{CF}V_C}{C_{TOT}} + \frac{C_{DF}V_D}{C_{TOT}} + \frac{(Q_F - Q_I)}{C_{TOT}}$$

$$\boxed{V_F - V_{TH}} = V_C + \frac{C_{DF}V_D}{C_{TOT}} + \frac{(Q_F - Q_I)}{C_{TOT}} - V_{TH} = \boxed{V_C - V_{THF}}$$

$$V_C - V_{THF} \simeq V_C - \left( V_{TH} - \frac{C_{DF}V_D}{C_{TOT}} + \frac{(Q_F - Q_I)}{C_{TOT}} \right)$$

$$V_{THF} = V_{TH} - \frac{C_{DF}}{C_{TOT}}V_D - \frac{Q_F}{C_{TOT}} + \frac{Q_I}{C_{TOT}}$$

# Organic Charge Modulated FET (OCMFET) – Working principle

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The shift of the effective threshold voltage depends on the charge, accumulated on the FG, and the total capacitance of the structure

$$\Delta V_{TH} = -\frac{\Delta Q}{C_{TOT}}$$



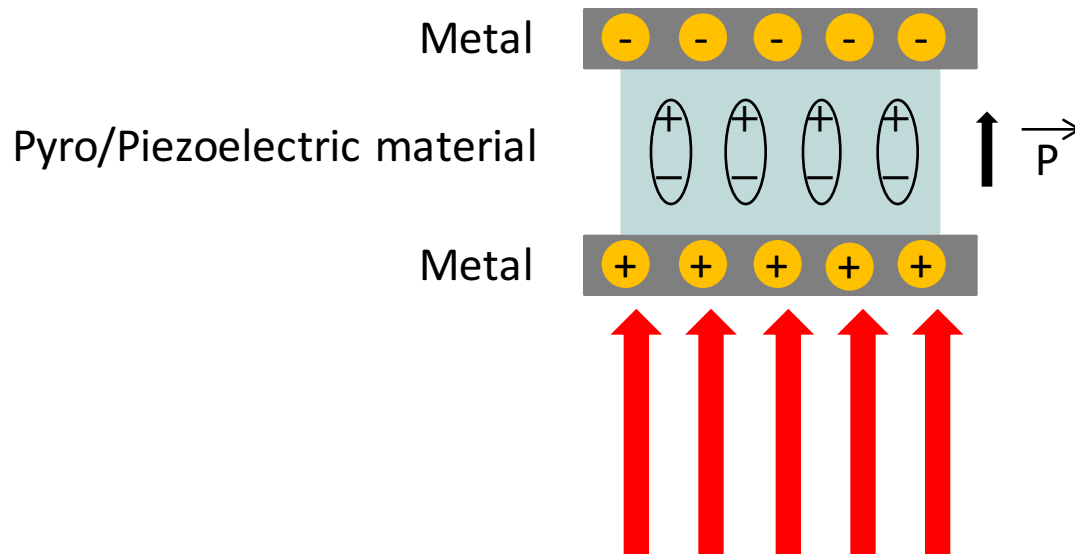
- Bio-chemical reactions
- Using sensible materials



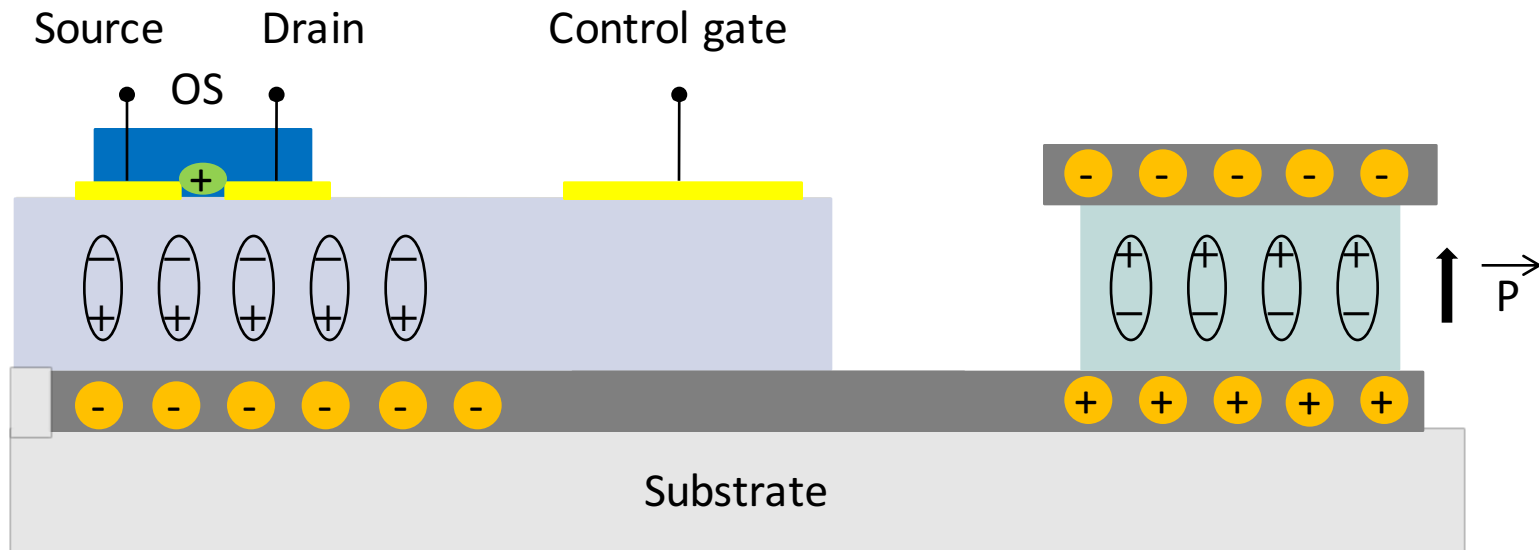
# OCCMFET as physical sensor

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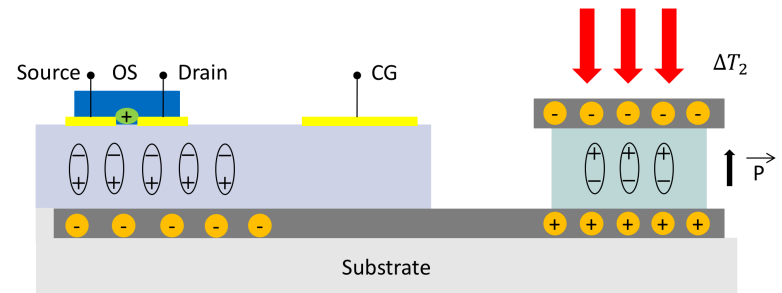
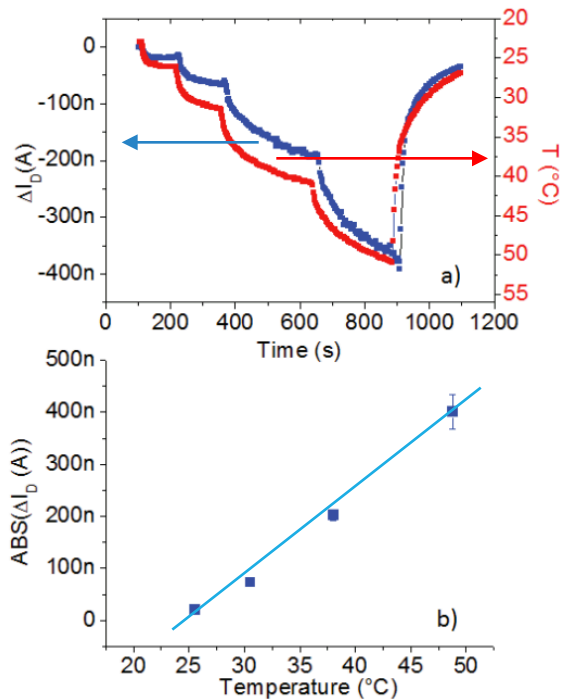
A temperature variation (or an applied force) induces a charge separation in the pyro/piezoelectric material



# OCCM-FET as physical sensor

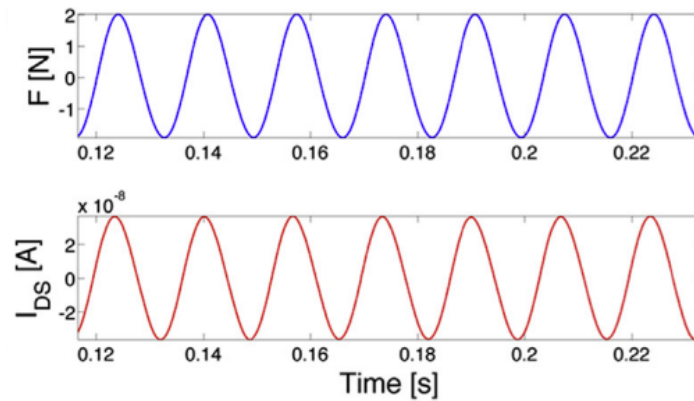
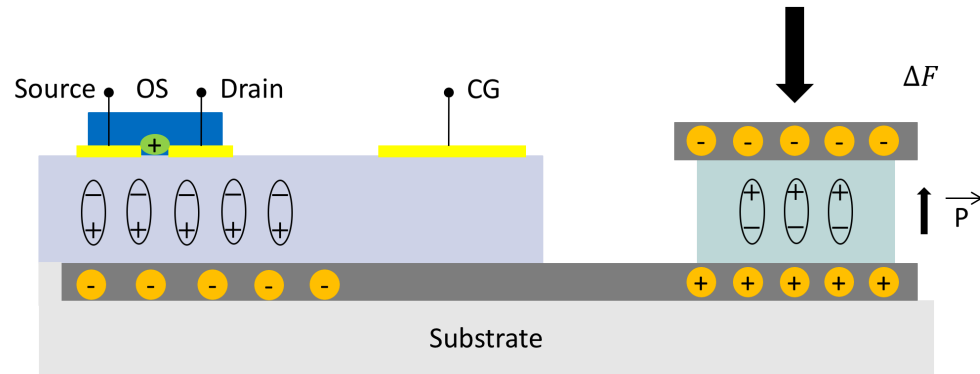


# OCMFET as physical sensor

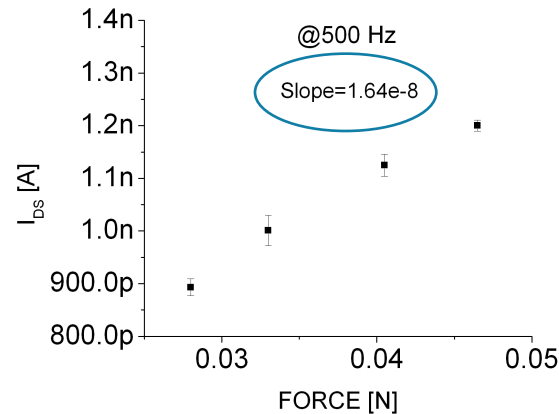
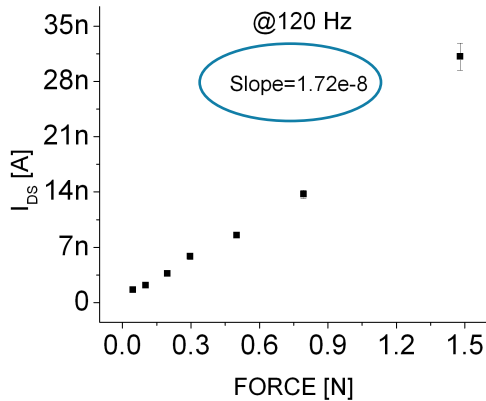
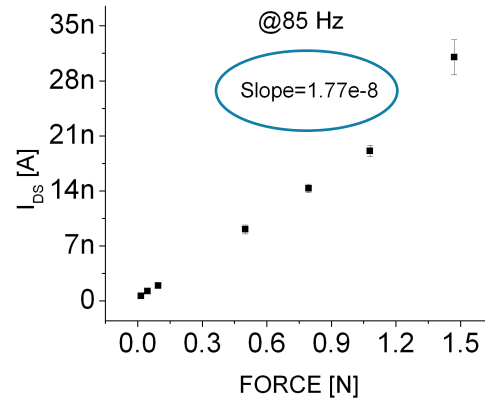
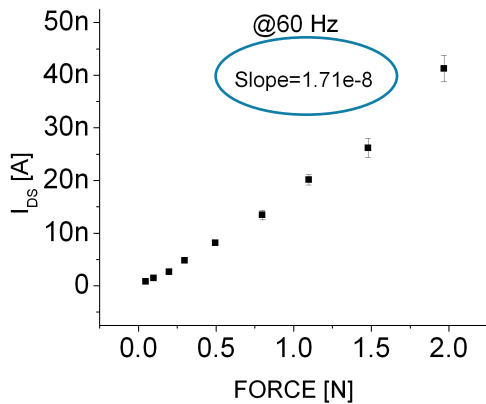


- Good reproducibility
- Quasi-linear response

# OCMFET as physical sensor



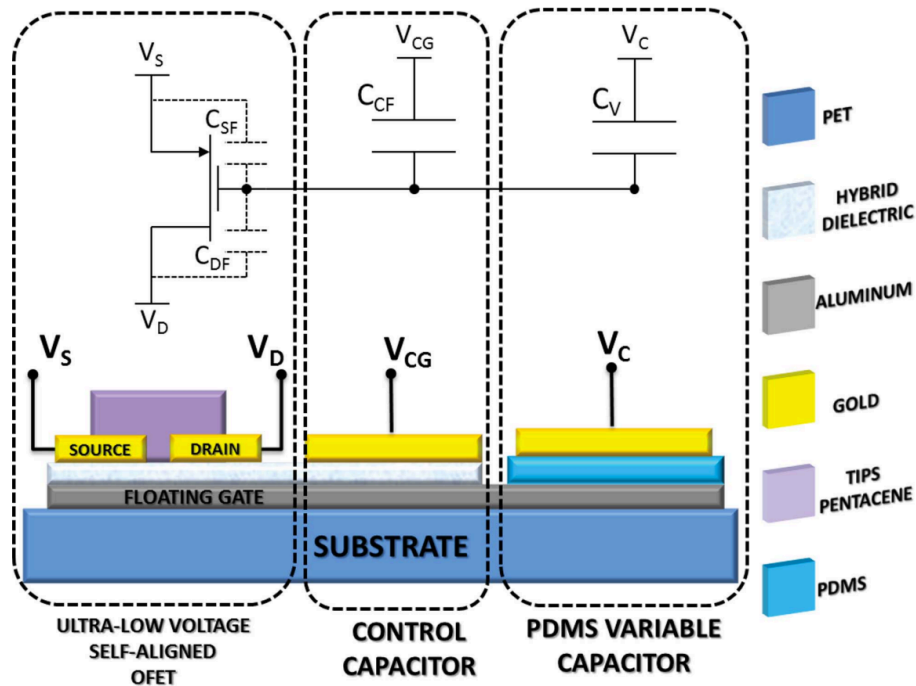
# OCMFET as physical sensor



- Linear behaviour
- Reproducible response
- Constant sensitivity
- High resolution

(low than 20 mN)

# Pressure-Modulated FET PMOFET

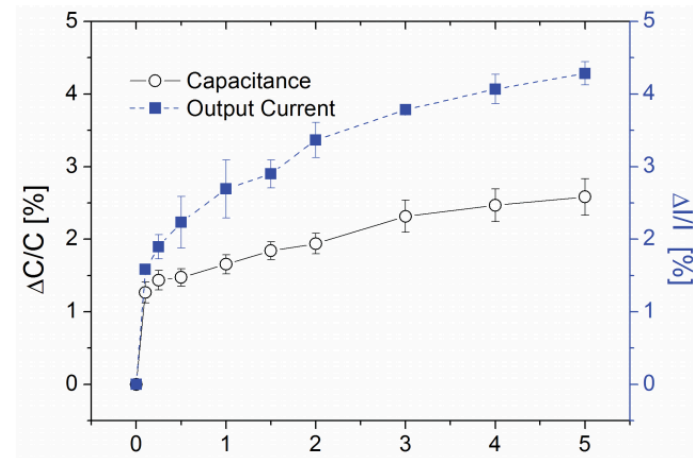
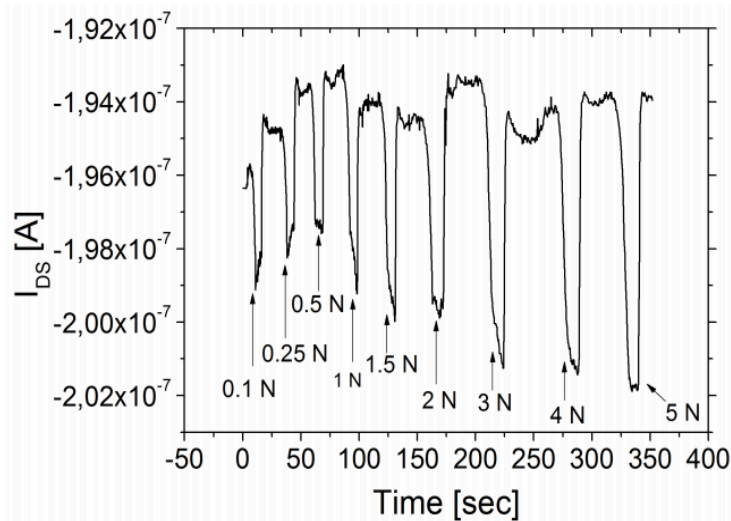


$$V_{FG} = \frac{C_{CF}}{C_{SUM}} V_{CG} + \frac{C_V}{C_{SUM}} V_C + \frac{Q_0}{C_{SUM}}$$

$$I_{DS} = k[(V_{FG} - V_{TH})V_{DS} - 0.5(V_{DS})^2]$$

# Pressure-Modulated FET PMOFET

Experimental results:



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Thanks for your kind  
attention